

IN THE CLAIMS

~~Add~~ the following claims:

--21. An optical microapparatus for use with a laser beam that extends along a path comprising a body having an inlet port adapted to receive the laser beam and a plurality of outlet ports, a plurality of reflectors carried by the body, a plurality of micromotors carried by the body, each of the micromotors having at least one electrostatically-driven comb drive assembly, attachment means for coupling the plurality of reflectors to the respective plurality of micromotors and a controller electrically coupled to the micromotors for providing control signals to the micromotors whereby each of the micromotors selectively moves the respective reflector from a first position out of the path of the laser beam to a second position into the path of the laser beam for directing light from the laser beam to an outlet port.

22. An optical microapparatus as in Claim 21 wherein the plurality of reflectors and plurality of micromotors include a first plurality of reflectors and corresponding micromotors and a second plurality of reflectors and corresponding micromotors, the first plurality of micromotors opposing the second plurality of micromotors relative to the path of the laser beam so that the path of the laser beam extends between the first plurality of micromotors and the second plurality of micromotors.

23. An optical microapparatus as in Claim 21 wherein each reflector comprises a layer of silicon and a layer of a reflective material adhered to the layer of silicon.

24. A micromachined reflector comprising a planar substrate, a reflective layer disposed over the planar substrate and at least one optically transparent quarter-wavelength thin film disposed over the reflective layer.

25. The micromachined reflector of Claim 24 wherein the reflective layer includes a gold layer.

26. The micromachined reflector of Claim 24 wherein the reflective layer includes an aluminum layer.

27. The micromachined reflector of Claim 24 further comprising an adhesion layer disposed between the reflective layer and the planar substrate for securing the reflective layer to the planar substrate.

28. The micromachined reflector of Claim 27 wherein the adhesion layer is

made of chromium.

29. The micromachined reflector of Claim 24 wherein the at least one optically transparent quarter-wavelength thin film includes a quarter-wavelength silicon dioxide thin film.

30. A micromachined reflector comprising a planar substrate, a reflective layer, means for securing the reflective layer to the planar substrate, a first dielectric layer of a material having a relatively low index of refraction overlying the reflective layer and a second dielectric layer of a material having a relatively high index of refraction overlying the first dielectric layer for increasing the reflectivity of the micromachined reflector.

31. A micromachined reflector as in Claim 30 for use with laser light having a wavelength wherein the first dielectric layer and the second dielectric layer each have an optical thickness equal to one-quarter the wavelength of the laser beam.

32. A micromachined reflector as in Claim 30 wherein the first dielectric layer is a material selected from the group consisting of magnesium fluoride and silicon dioxide.

33. A micromachined reflector as in Claim 30 wherein the second dielectric layer is a material selected from the group consisting of cerium oxide and titanium.

34. A micromachined reflector as in Claim 30 wherein the reflective layer is a material selected from the group consisting of gold, silver and aluminum.

35. A micromachined reflector as in Claim 30 wherein the means for securing the reflective layer to the planar substrate is an adhesion layer.

36. A micromachined reflector as in Claim 35 wherein the adhesion layer is a material selected from the group consisting of chromium and titanium.

37. A micromachined reflector as in Claim 30 further comprising an additional first dielectric layer of a material having a relatively low index of refraction overlying the second dielectric layer and an additional second dielectric layer of a material having a relatively high index of refraction overlying the additional first dielectric layer.

REMARKS

The specification has been amended to reflect the applications to which priority is